

Metals > MBE Components

MBE Components
Components for Molecular Beam Epitaxy

Effusion Cells

Standard Effusion Cell - WEZ	Organic Material Effusion Cell - OME
Mini Effusion Cell - MEZ	High Temperature Effusion Cell - HTEZ
Production Effusion Cell - PEZ	High Temperature Source - HTS
Low Temperature Effusion Cell - NTEZ	Oxygen Resistant Effusion Cell - OREZ

Valved Sources

Valved GaP Compound Source - VGCS	Valved Arsenic Cracker Source - VACS
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Electron Beam Evaporators

Standard E-Beam Evaporator - EBV	Vertical E-Beam Evaporator - EBVV
Multi-Pocket E-Beam Evaporator - EBVM	HV Power Supplies for EBV Series

Dopant Sources

Silicon Sublimation Source - SUSI	Dual Dopant Source - DCS
Carbon Sublimation Source - SUKO	

Dopant Source Materials

Gallium Phosphide Cubes - 6N Pure	Monocrystalline Silicon - >1000 Ohm/cm
Single Crystal, 0.5g	Shaped to fit customer's crucibles, 2cc - 500cc

Gas Sources

Hydrogen Atom Beam Source - HABS	Gas Cracker Cell - GRZ
Hydrogen Cracker Source - HCS	Thermal Gas Injector - TGI

MBE/UHV Systems

Research MBE Systems	In-Situ Etching Systems - ISES
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Equipment

Substrate Manipulator - SH	Cross Beam Ionizer - CBI
Power Supply, Temperature Control - PS	Shutter Control Unit - SCU
Thermocouples - TC	Shutter - S
Cables and Connectors - CA	Soft Acting Rotary Shutter Module - RSM
Manipulator Control Unit - MCU	Soft Acting Linear Shutter Module - LSM
Cryopump Valve Control Unit - CVCU	Magnetic Rotary Feedthrough - MRD
Beam Flux Monitor - BFM	Viewport Shutter - FSH
Cooling Shroud - CS	Crucibles - CRU